EE243 Advanced Electromagnetic Theory Lec # 25 Imaging as Diffraction (Cont.)

- Standing Waves in Films on Substrates
- Phasor Perturbational Images of Small Features
- Aberrations
- Interferometric Measurements
 - Phase Contrast; Point Spread; Pattern-and-Probe

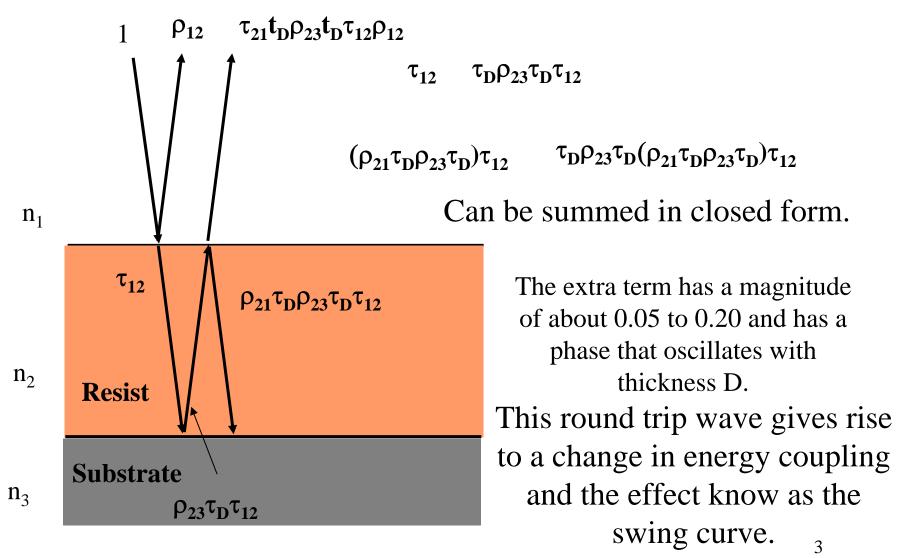
Reading: (This lecture is self contained and is based on excerpts from Born and Wolf Chapters 8 and 9 plus Chapter by Smith in Sheats and Smith)

Overview

Optical imaging also involves many other engineering aspects:

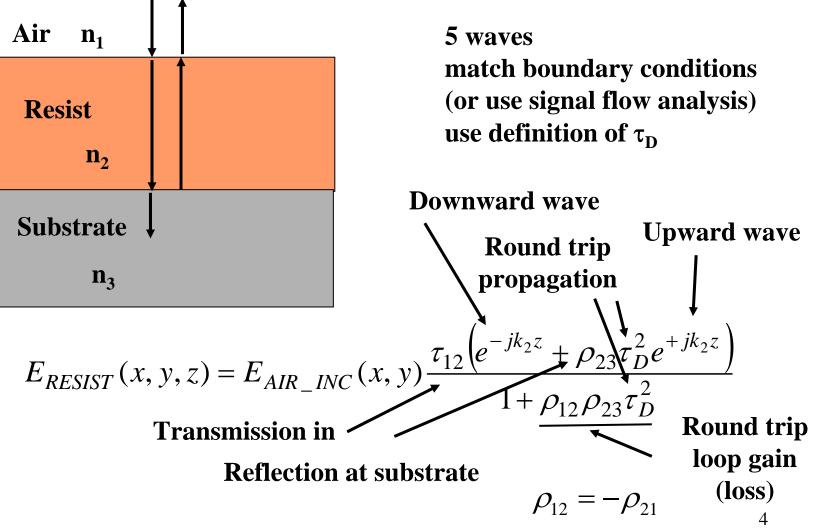
- Standing waves in films on substrates
- Pertubational methods for images of small features
- Aberrations and Strehl Ratio effects
- Phase interferometric measurement concepts
- Partial coherence of the illumination on a mask

Recording Media on a Substrate



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Electric Field within Resist



Waves in Recording Media

The wavelength in the media is shorter and waves are attenuated

$$n = n_r + jn_i$$

$$k_m = \left(n_r + jn_i\right)k_{air} = \left(n_r + jn_i\right)\frac{2\pi}{\lambda_{air}}$$

$$n_r \Rightarrow \lambda_m = \frac{\lambda_{air}}{n_r} \qquad n_i \le 0 \rightarrow \text{attenuation}$$

To match the lateral variation across the air resist interface

$$k_{m_x} = k_{air_x}$$
 $k_{m_y} = k_{air_y}$
Snell's Law $\sin \theta_m = \frac{\sin \theta_{air}}{n_r}$

Reflection and Transmission

Reflection and transmission coefficients in going from media i to media j

$$\rho_{ij} = \frac{n_i - n_j}{n_i + n_j} \qquad \qquad \tau_{ij} = \frac{2n_i}{n_i + n_j} \qquad \qquad \text{Note: } \mathbf{1} + \rho = \tau$$

Phase change and attenuation with distance z

Example: air to quartz ($n_{qz} = 1.5$); $\rho = -0.2$ and $\tau = 0.8$

$$\tau(z) = e^{-j(n_r + jn_i)\frac{2\pi}{\lambda_{air}}z}$$

Example: complex propagation factor in going from z=0 to z=D is

$$\tau_D = e^{-j(n_r + jn_i)\frac{2\pi}{\lambda_{air}}D}$$

The same net complex factor occurs for the upward wave in going from z=D to z=0.

Standing Wave Models (365 nm Example)
Shipley 511A (neglecting n_i)

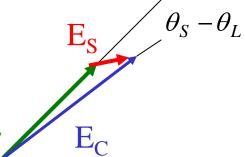
$$n_{RESIST} = 1.7$$
 $n_{SUB} = 6.52 - j2.71$
 $\rho_{RESIST} = \frac{n_{RESIST} - n_{SUB}}{n_{RESIST} + n_{SUB}} = 0.64 \angle 179.5^{\circ}$
 $E_{MAX} = 1 + |\rho| = 1.64$ $E_{MIN} = 1 - |\rho| = 0.36$
 $I_{MAX} = (1 + |\rho|)^2 = 2.87$ $I_{MIN} = (1 - |\rho|)^2 = 0.13$
 $C_{VERTICAL} = \frac{I_{MAX} - I_{MIN}}{I_{MAX} + I_{MIN}} = \frac{2.87 - 0.13}{2.87 + 0.13} = 0.91$

Perturbation Model of Image Contributions $(1+x)^2 = 1+2x+x^2$ $(1+0.1)^2 = 1+0.2+0.01$

Consider a composite electric field made up of a large electric field and a small electric field that are time- harmonic, possibly out of phase and oriented in a co-linear direction.

$$E_C = E_L + E_S = E_L e^{j\theta_L} + E_S e^{j\theta_S}$$

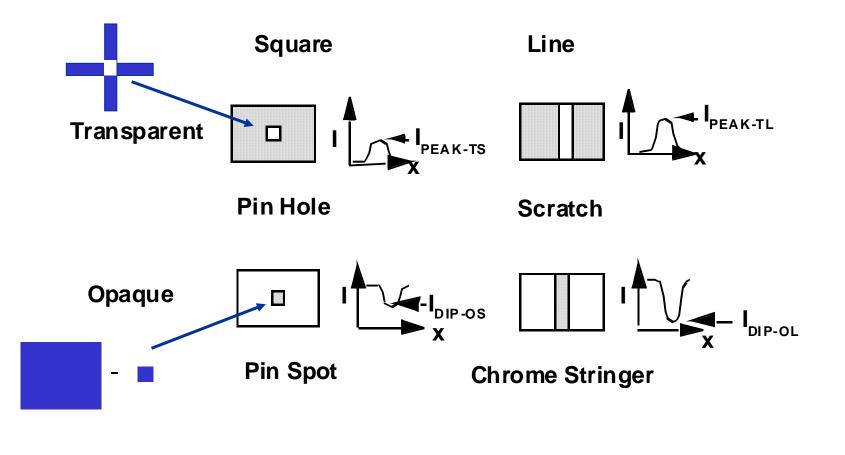
The intensity is proportional to the electric field times its conjugate



Phasor Diagram in complex plane

$$I = \overline{E}_{C} \cdot \overline{E}_{C}^{*} = |E_{L}|^{2} + E_{L}E_{S} 2\operatorname{Re}\left[e^{j(\theta_{S}-\theta_{L})}\right] + |E_{S}|$$
$$I = I_{L} + \sqrt{I_{L}}\sqrt{I_{S}} 2\operatorname{Re}\left[e^{j(\theta_{S}-\theta_{L})}\right] + I_{S}$$
$$\operatorname{Small}$$
Very Small

Basic Types of Small Features



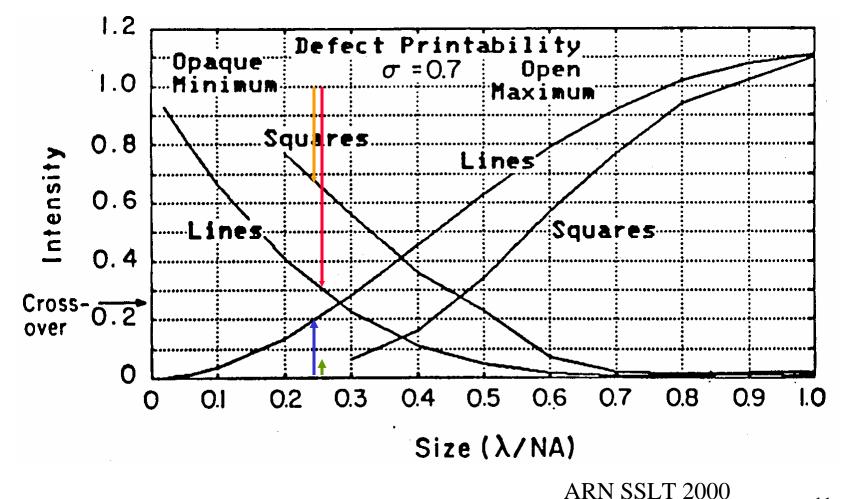
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Intensity Models for Small Features

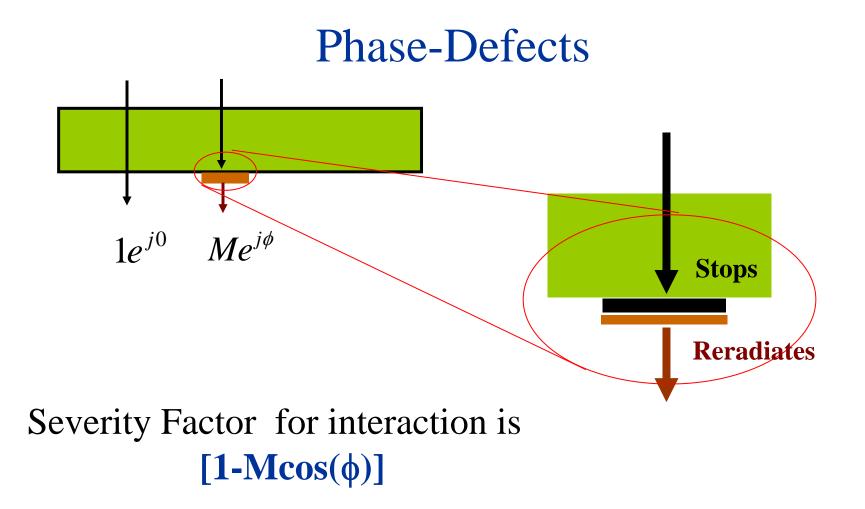
$$s = square, L = Line$$
 $T = Transparent, O = Opaque$
 $I_{PEAK-TS} = 8.5 [d/(\lambda/NA)]^4$
 $I_{PEAK-TL} = sqrt(I_{PEAK-TS})$
 $I_{DIP-OS} = 1 - 2 sqrt(I_{PEAK-TS})$
 $I_{DIP-OL} = 1 - 2 sqrt[sqrt(I_{PEAK-TS})]$

Small mask openings produce a point spread shaped distribution with an intensity proportional to the square of the area.

Peak and Minimum Intensity for Small Features

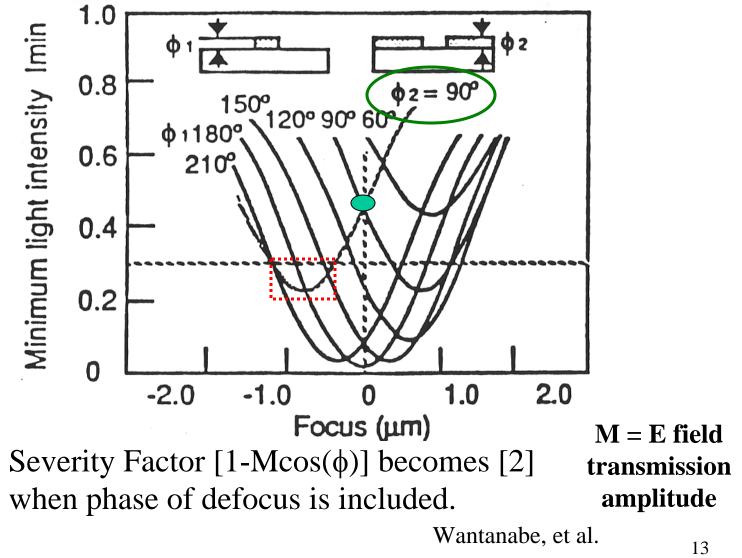


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Worst case is a **factor of 2** when $\phi = 180^{\circ}$

Phase Defects May Print Worse Out of Focus



EE 210 Applied EM Fall 2006, Neureuther

Optical Path Difference

The optical path difference (OPD) is the phase error over the pupil between rays for the actual lens and those for a perfect diffraction limited lens.

Born and Wolf 7th ed, Ch 9

The OPD is usually normalized to wavelengths.

The OPD contributes an additional phase factor of $e^{j(2\pi/\lambda)OPD}$ in the integration of the rays in computing the electric field at the image.

For primary aberrations like tilt, defocus, spherical, coma, and astigmatism a power series is used

$$\Phi = A'_{n,m}\rho^n \cos^m \theta$$

Zernike introduced the so called "circle polynomials" that are **orthonormal on the unit circle** to describe aberrations.

$$\Phi = A_{00} + \frac{1}{\sqrt{2}} \sum_{n=2}^{\infty} A_{n0} R_n^{\infty}(\rho) + \sum_{n=1}^{\infty} \sum_{m=1}^n A_{nm} R_n^m(\rho) \cos m\theta \qquad \qquad R_n^{\pm m}(1) = 1$$

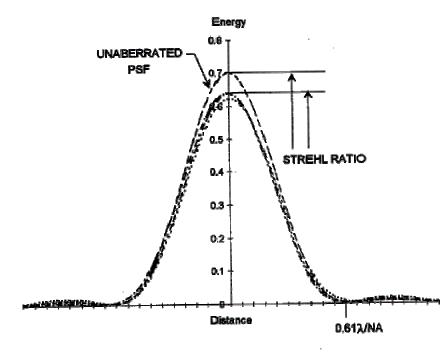
Primary Coma => orthogonal components => tilt + balanced₁**coma** Copyright 2006 Regents of University of California

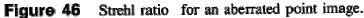
Expansion of Zernike

Table 2 Fringe Zernike Polynomial Coefficients and Corresponding Aberrations*

Term	Fringe Zernike Polynomial	Aberration	
1	1	Piston	
2	$r\cos(\alpha)$	X Tilt	
3	$r \sin(\alpha)$	Y Tilt	The Zernike polynomials
4	$2r^2 - 1$	Defocus	
5	$r^2 \cos(2\alpha)$	3rd Order astigmatism	are individual functional
б	$r^2 \sin(2\alpha)$	3rd Order 45° astigmatism	variations in radius r and
7	$(3r^3-2r)\cos{(\alpha)}$	3rd Order X coma	variations ni rautus rantu
8	$(3r^3-2r)\sin(\alpha)$	3rd Order Y coma	angle α in an orthonormal expansion over the lens pupil normalized to radius 1. Z2 Tilt in x is r cos(α)
9	$(6r^4 - 6r^2) + 1$	3rd Order spherical	
10	$r^3 \cos(3\alpha)$		
[]	$r^3 \sin(3\alpha)$		
12	$(4r^4 - 3R^2)\cos(2\alpha)$	5th Order astigmatism	
13	$(4R^4 - 3R^2) \sin(2\alpha)$	5th Order 45° astigmatism	
14	$(10r^3 - 12r^3 + 3r)\cos{(\alpha)}$	5th Order X coma	
15	$(10r^3 - 12r^3 + 3r) \sin(\alpha)$	5th Order Y coma	
16	$20r^6 - 30r^4 + 12r^2 - 1$	5th Order spherical	
17	$r^4 \cos (4\alpha)$		Z7 is Coma in x
18	$r^{2} \sin (4\alpha)$		
19	$(5r^3 - 4r^3)\cos(3\alpha)$		with Tilt removed
20	$(5r^3-4r^3)\sin(3\alpha)$		
21	$(15r^6 - 20r^4 + 6r^2)\cos(2\alpha)$	7th Order astigmatism	or so called
22	$(15r^6 - 20r^4 + 6r^2) \sin(2\alpha)$	7th Order 45° astigmatism	balanced coma.
2 3	$(35r^7 - 60r^3 + 30r^3 - 4r)\cos(\alpha)$	7th Order X coma	balanceu coma.
24	$(35r^7 - 60r^3 + 30r^3 - 4r) \sin(\alpha)$	7th Order Y coma	
25	$70r^8 - 140r^6 + 90r^4 - 20r^2 + 1$	7th Order spherical	
26	$r^3 \cos(5\alpha)$		Sheats and Smith, pp. 224
27	$r^3 \sin(5\alpha)$		15
28	$(6r^6 - 5r^4) \cos (4\alpha)$ $(6r^6 - 5r^4) \sin (4\alpha)$ Copyright 2006 Regent	s of University of Californ	
29	(fr? = 5r) sin (4m~upyright 2000 Regent	s of University of Callorn	ua

Strehl Ratio





RMS OPD = (P-V OPD)/3.5

The peak value of the point spread function decreases proportionally to the square of the RMS value of the aberrations present.

The Strehl Ratio is defined as the ratio of the peak value with aberrations to the peak value without aberrations.

The Strehl Ratio is approximately **1-** $4\pi^2$ (**RMS OPD**)²

Sheats and Smith pp 255 16

Finding the Strehl Ratio $E(\bar{x}) = \frac{1}{\pi} \int_{0}^{2\pi} \int_{0}^{1} E(r,\alpha) e^{-j\bar{k}\cdot\bar{x}} e^{-jkOPD(r,\alpha)} r \delta r \delta \alpha$

To find the Strehl ratio (relative value the peak intensity in the presence of an aberration) we only need look at x = 0and assume that E(r,a) is produced by a small pin hole and thus constant. This greatly simplifies the integral to

$$E(0) = \frac{1}{\pi} \int_{0}^{2\pi} \int_{0}^{1} e^{-jkOPD(r,\alpha)} r \delta r \delta \alpha$$

When the OPD is small

$$E(0) = \frac{1}{\pi} \int_{0}^{2\pi} \int_{0}^{1} [1 - jkOPD(r,\alpha) - \frac{k^2}{2}OPD^2(r,\alpha)]r \delta r \delta \alpha = 1 - jk\overline{\Phi} - \frac{k^2}{2}\overline{\overline{\Phi}}$$

Where $\overline{\overline{\Phi}}$ is the average of OPD² over the pupil

The intensity is given by

$$|E(0)|^{2} = \left|1 - jk\overline{\Phi} - \frac{k^{2}}{2}\overline{\Phi}\right|^{2} = \left|1 - \frac{k^{2}}{2}\overline{\Phi} - jk\overline{\Phi}\right|^{2} \approx 1 - k^{2}\overline{\Phi} + k^{2}(\overline{\Phi})^{2} = 1 - 4\pi^{2}\overline{\Phi} = 1 - 4\pi^{2}\sum_{n,m}\overline{\Phi}_{n,m} = 1 - 4\pi^{2}\sum_{n,m}A_{n,m}^{2}$$
Zero for Zernike's 17
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Zernike Phase Contrast Microscopy 1935 Nobel Prize 1953

$$F(x) = e^{i\phi(x)} \approx 1 + i\phi(x)$$

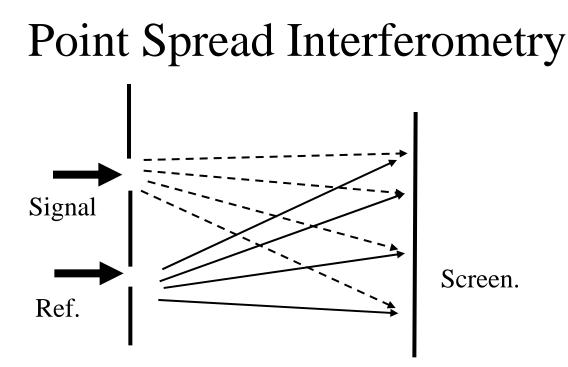
$$F(x) = \sum_{n} c_{m} e^{i\frac{2\pi}{P}x}$$

$$c_{0} = 1, c_{-m} = -c_{m}^{*}$$

$$G(x) = \pm i + i\phi(x)$$

$$I(x) = |G(x)|^{2} = 1 \pm 2\phi(x)$$

- A phase object must be imaged in many applications such as in Biology
- For a periodic phase object $\phi(x)$ with the Taylor series approximation the spectrum is 1 for the D.C. term and imaginary for the higher order terms.
- A phase plate is added to shift the D.C. order by + or 90 degrees
- A real (but fictitious) image proportional to the phase is produced.



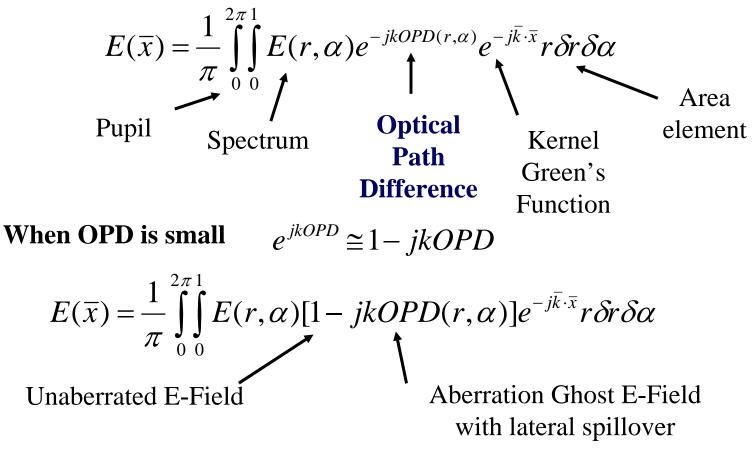
• A reference signal is introduced by using light from a pin hole or scatterer

• The signal under test then interacts with the reference signal spreading from the point

• Computer analysis of the resulting interference fringes on the screen allow the phase of the signal to be determined.

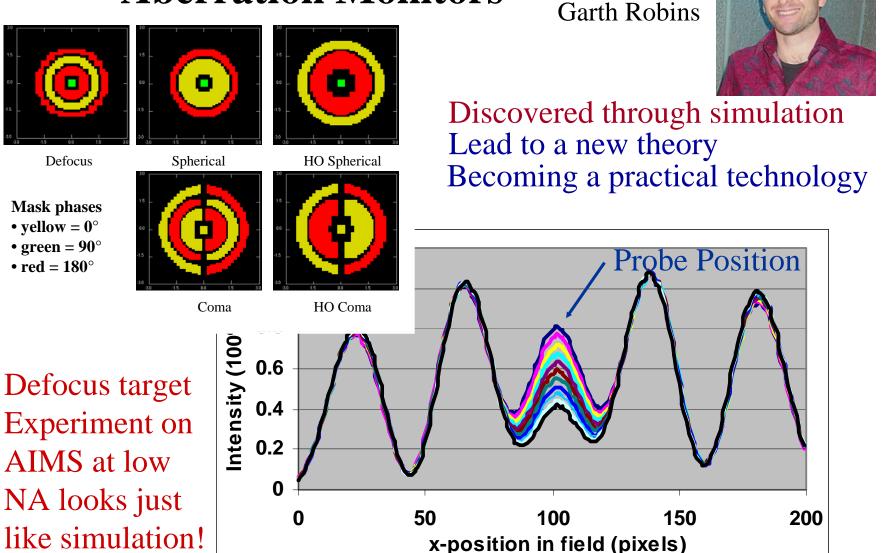
Mathematics of Aberrations and OPD

The electric field produce by the convergence of the cone of plane waves from the pupil at any point x on the wafer is given by integrating the waves over the pupil.

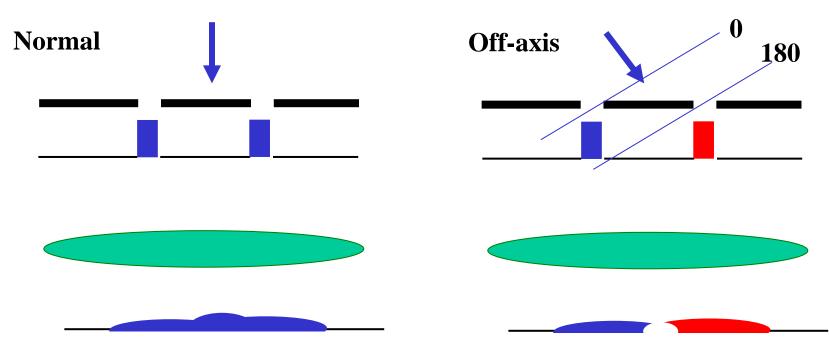


EE 210 Applied EM Fall 2006, Neureuther Pattern-and-Interferometric-Probe Aberration Monitors

Lecture #25 Ver 11/19/06



Illumination Controls Proximity Effects Two Pinholes in a mask



$$I_{TOTAL} = E_1^2 + 2E_1E_2 + E_2^2$$

$$I_{TOTAL} = E_1^2 - 2E_1E_2 + E_2^2$$

- Wafer
 - Tails of electric field overlap (spillover)
 - Relative phases depend on phase of illumination Copyright 2006 Regents of University of California

Mutual Coherence of Illumination

$$\mu_{21} = \mu(\overline{x}_{2}, \overline{x}_{1}) = \sum_{m} \sum_{n} \frac{E_{m}(\overline{x}_{1})E_{n}(\overline{x}_{2})^{*}}{|E_{m}(\overline{x}_{1})||E_{n}(\overline{x}_{2})|}$$

$$m \neq n \Rightarrow 0$$

$$E_{n}(\overline{x}_{2}) = |E_{n}(\overline{x}_{1})|e^{-j\overline{k}_{n}(\overline{x}_{2}-\overline{x}_{1})}$$

$$\mu_{21} = \mu(\overline{x}_{2} - \overline{x}_{1}) = \sum_{n} e^{+j\overline{k}_{n}(\overline{x}_{2}-\overline{x}_{1})}$$

$$\mu_{21} = F.T.(Source_Shape)|_{(\overline{x}_{2}-\overline{x}_{1})}$$

- Defined as time-average normalized cross-product •
- Assuming that illumination waves from different angles are incoherent the cross terms all drop out
- For a given source angle (k-vector) field at x_2 found from field at x_1 •
- Sum for a uniform source is just the Fourier transform or the source • shape

Mutual Coherence Function

 $I_{TOTAL}(x) = E_1^2(x) + 2\operatorname{Re}\left\{\mu(x_2 - x_1)E_1(x)E_2(x)\right\} + E_2^2(x)$

- Measures the complex degree of coherence between any two points on the mask.
- Is a function only of the distance and angle between the two points and not their absolute positions.
- The value is given by the inverse Fourier transform of the wave angles and magnitudes that make up illumination. (The temporal phases are incoherent)
- For a disk of illumination of radius σNAk_0 it is the Airy function with argument $|x|/\sigma$.
- Thus the signal is relatively coherent over most of a spot $1/\sigma$ times the point spread function (i.e. $(1.22/\sigma)\lambda/NA$).

Mutual Coherence Function: Top Hat

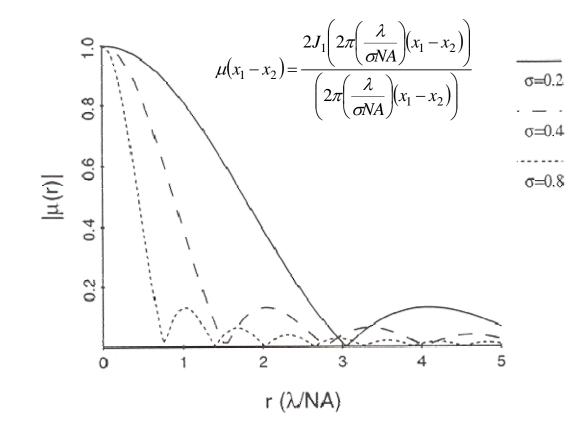


Figure 2.22: For any partial coherence factor, the degree of coherence $|\mu(\hat{r})|$ has the same shape except for a scaling of the x-axis by $(1/\sigma)$.

Aerial Image Intensity for Knife Edge

